Customer No.: 31561 Application No.: 10/063,975

Docket No.: 8642-US-PA

AMENDMENTS

In The Claims

1. (original) A method of spiking a mixed acid liquid in a reactor by using a

computer to control a concentration of the mixed acid liquid, the concentration of the

mixed acid liquid being controlled at a target level under a based-on-charge mode, a based-

on-time mode, or a based-on-time-and-charge mode,

the based-on-charge mode control comprising:

providing a charge list including a plurality of lot numbers of product and a

plurality of spiking amounts of a first acid liquid corresponding lot numbers of product;

and

introducing the spiking amounts of the first acid into the reactor in an order

corresponding to the lot numbers of product;

the based-on-time mode control comprising:

providing a timing list including a plurality of timing points and a plurality

of spiking amounts of a second acid liquid corresponding to the timing points;

and

introducing the spiking amounts of the second acid liquid into the reactor at

the corresponding timing points;

and the based-on-time-and-charge mode control comprising:

2

Customer No.: 31561

Application No.: 10/063,975 Docket No.: 8642-US-PA

providing a charge/timing list including spiking amounts and spike timing

points; and

introducing the spiking amounts of the first acid into the reactor based on

the lot numbers of product and the spike timing points.

2. (original) The method of claim 1, wherein when a wafer is being etched in the

reactor, the acid liquid is not introduced into the reactor.

3-7. (Canceled)

8. (original) A method of spiking a mixed acid liquid in a reactor by using a

computer to control a concentration of the mixed acid liquid, the concentration of the

mixed acid liquid being controlled at a target level under a based-on-time-and-charge

mode,

wherein the based-on-time-and-charge mode control comprises:

providing a charge/timing list including spiking amounts and spike timing

points; and

introducing the spiking amounts of the first acid into the reactor based on lot

numbers of product and the spike timing points.

9. (original) The method of claim 8, wherein when a wafer is being etched in the

reactor, the acid liquid is not introduced into the reactor.

3